

III-Nitride Nanowires: Novel Materials for Solid-State Lighting

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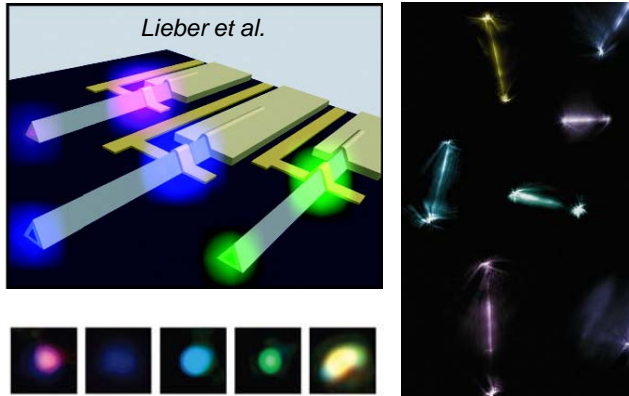
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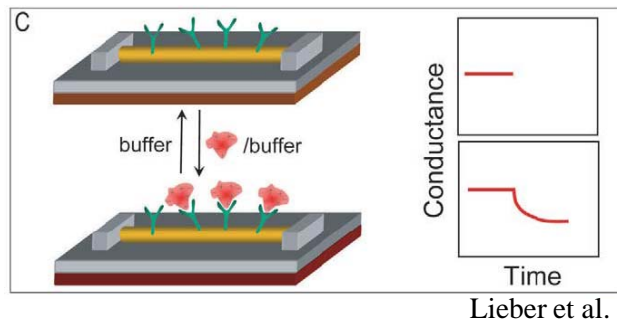
Semiconductor Nanowires (NWs)

Reduced dimensionality, high crystalline quality, high atomic surface/bulk ratio, size (intersects physical characteristic length scales) can lead to enhanced & novel properties



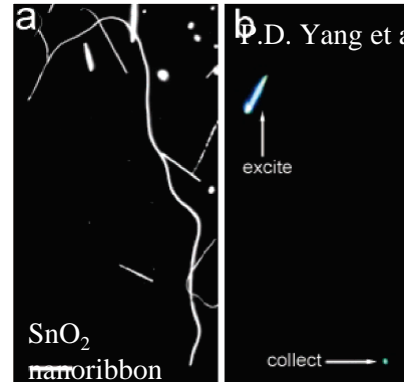
LEDs and lasers

- Nanosized light sources
- Higher efficiency due to lack of defects
- High light extraction



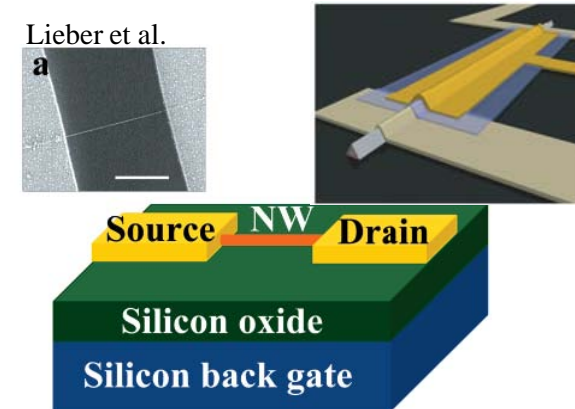
Chem/bio-sensors

- large atomic surface/bulk ratio leads nanowire depletion & ultrahigh sensitivity



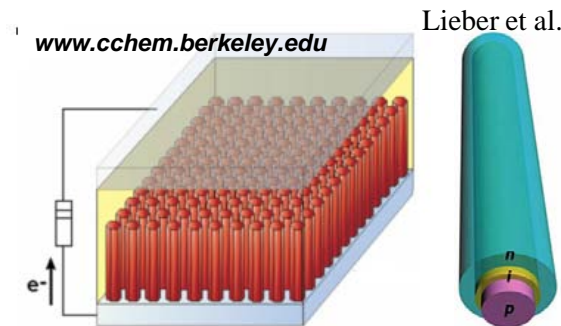
Waveguides and Filters

- coupled with nanowire light sources, building blocks for nanophotonics circuitry



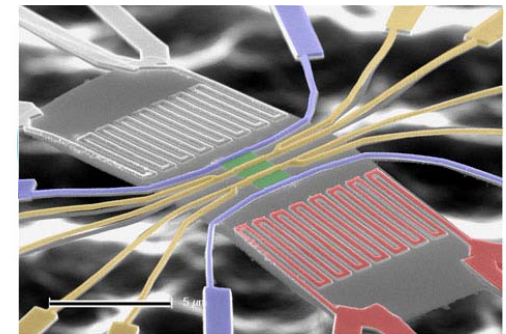
Transistors/HEMTs

- improved performance characteristics
- small size



Energy Harvesting

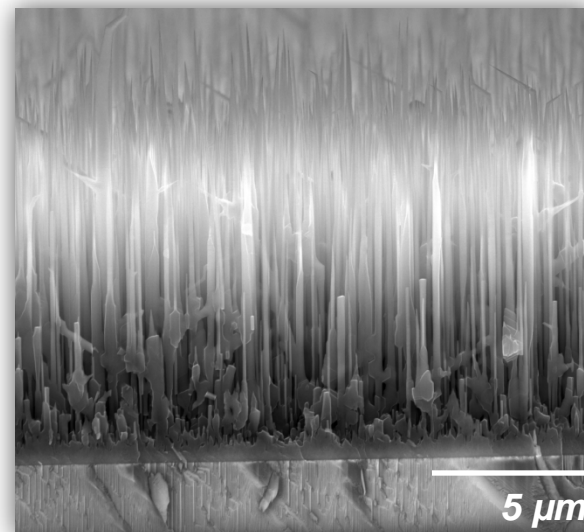
- Nanowire Photovoltaics
- Thermoelectrics
- Piezoelectric energy generation



III-Nitride (AlGaInN) nanowires for SSL

Compared to planar films, III-nitride nanowires ...

- Have high light extraction efficiencies
- Are strain relaxed
 - can accommodate wider range of alloy compositions (wide color space)
 - typically free of threading dislocations (IQE)
 - can grow on any substrate (cost)
- Are “discrete” – entire structure & changes to the structure can be investigated

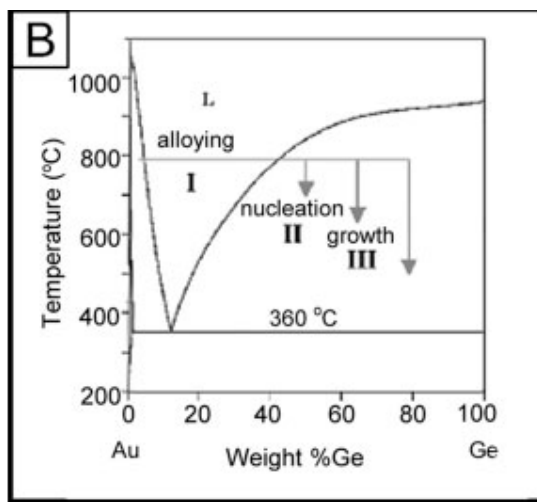
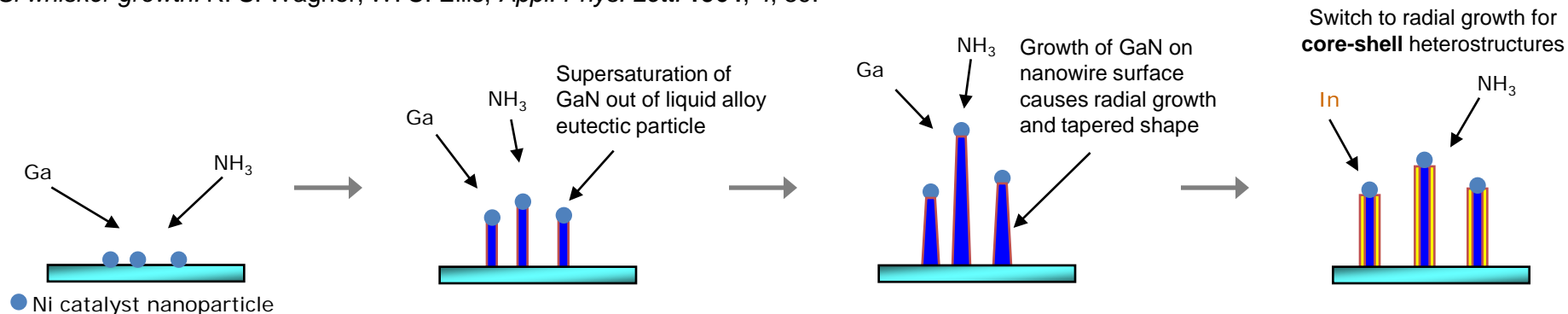


Challenges for nanowire-based LEDs & other devices:

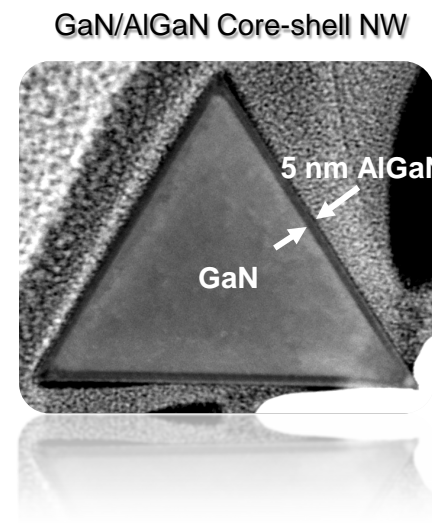
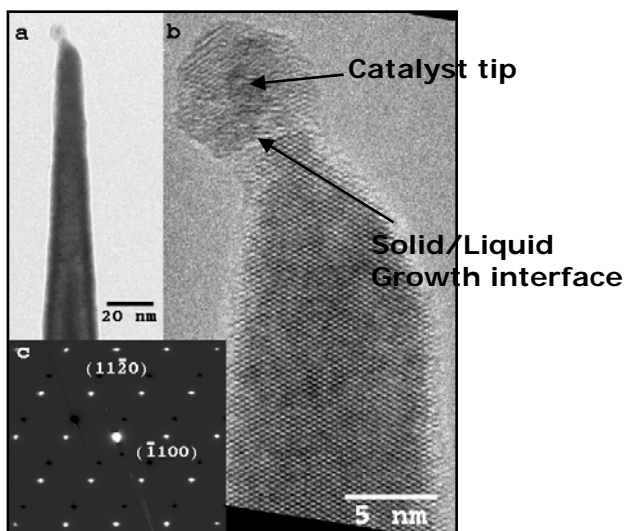
- Understanding & control of synthesis – size, length, alignment, facets, uniformity
- Understanding & control of properties – electrical, optical, thermal, mechanical, etc.
- Device integration – contacts, surface states, single nanowire & vertical integration schemes

Vapor-liquid-solid (VLS) based nanowire growth

Si whisker growth: R. S. Wagner, W. C. Ellis, *Appl. Phys. Lett.* **1964**, 4, 89.

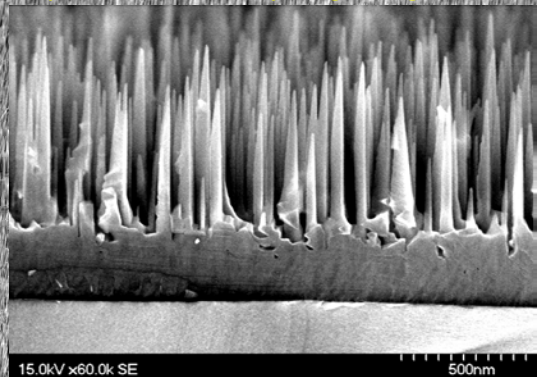


From Xia et al. *Adv. Mater.* **2003**, 15, 353.

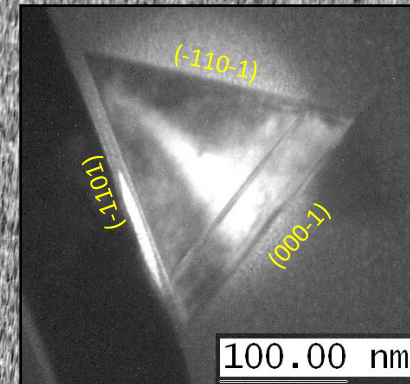
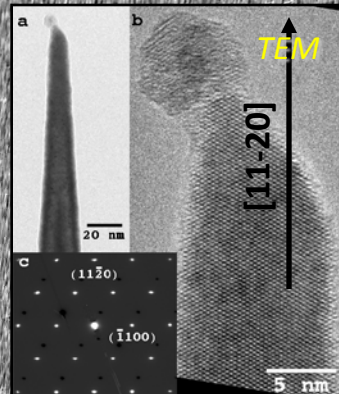


Aligned GaN nanowire growth

Epitaxial vertically aligned growth



[11-20]



- Nanowires grown by Ni-catalyzed MOVPE/MOCVD (VLS)
- Highly-aligned, uniform vertical growth over large areas (2" r-sapphire wafer)
- Controllable densities as high as ~ 150 nanowires μm^{-2}

Q. Li, G. T. Wang, *Appl. Phys. Lett.* 93, 043119 (2008)

Q. Li, J. R. Creighton, G.T. Wang *J. Cryst. Growth* 310 3706-3709 (2008)

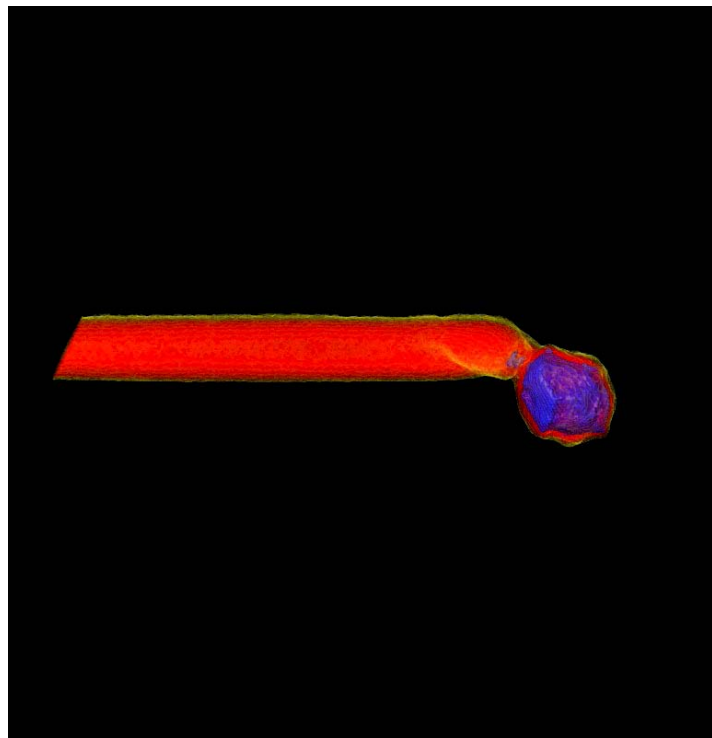
- Primary [11-20] growth orientation (\perp to (11-20) α -plane)
- Triangular faceted -- (000-1) and equiv. (-1101) and (-110-1)
- TEM: Single crystal, dislocation free; c -plane stacking faults

G. T. Wang et al., *Nanotechnology* 17 5773-5780 (2006)



3D imaging of core-shell NWs by STEM tomography

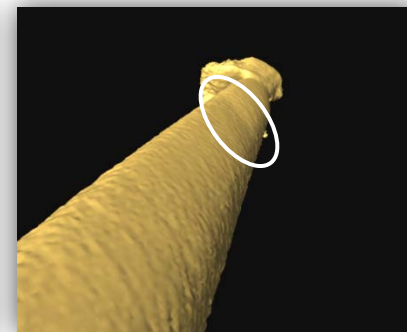
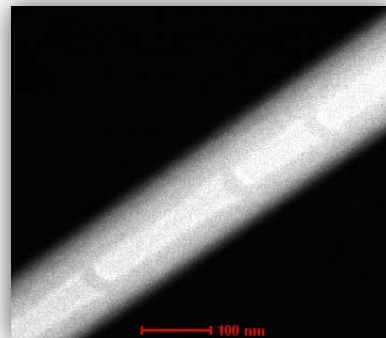
Goal: 3D morphology of heterostructure nanowires



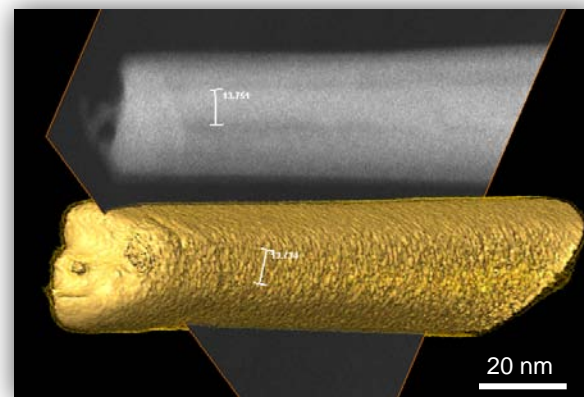
GaN-AlN core-shell NW

50 nm

Tilt Range:
-73 to +70 °
144 Images

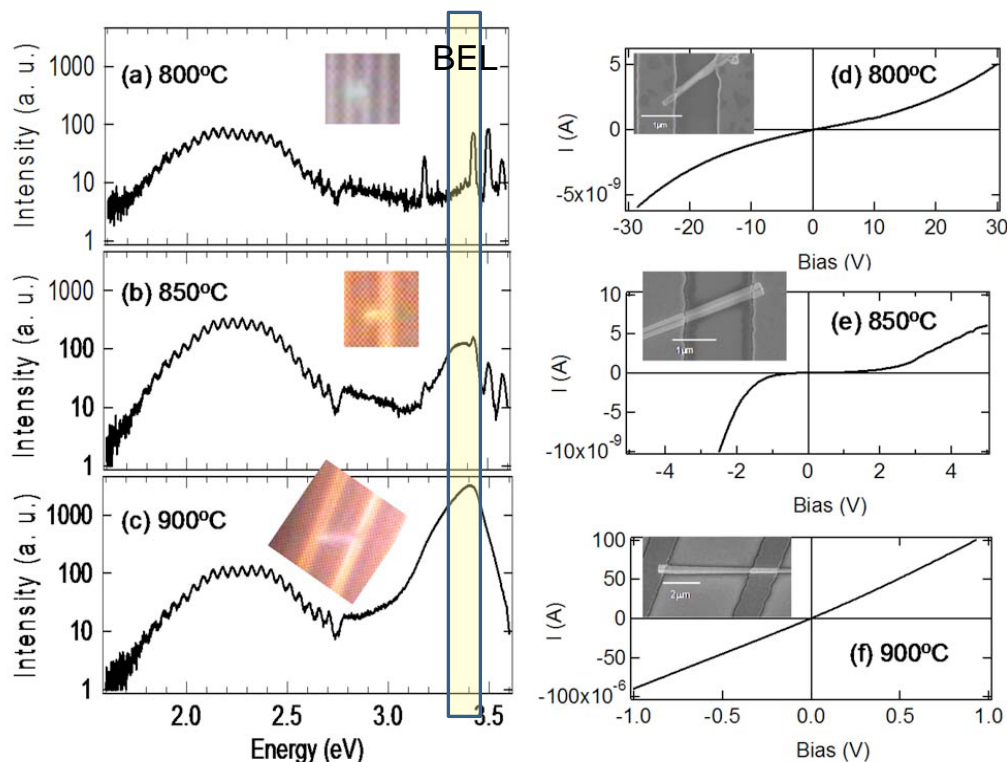


“Breaks” in GaN core from 2D STEM images revealed instead by 3D tomography as *surface notches*

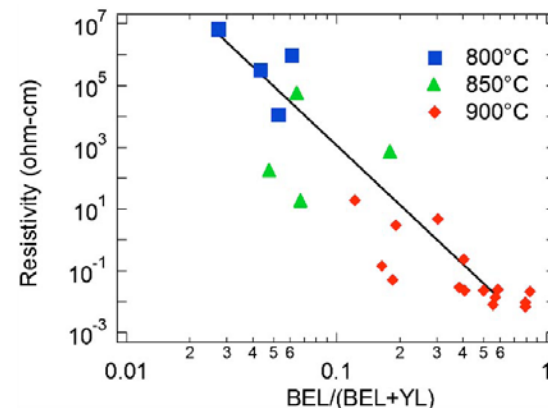


Bright center strip revealed by 3D tomography as extra facet, not GaN core

μ PL and I-V measurements: Impact of NW growth temperature



Optical/electrical NW device platform

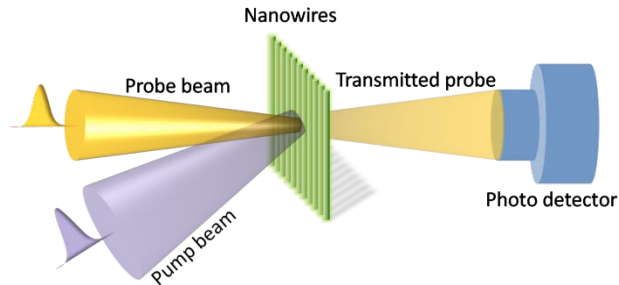


- ~50x increase in band-edge emission at 900 °C vs 800 °C
- Resistivity ~ 6 orders of magnitude lower at 900 °C vs 800 °C
- Yellow luminescence (YL) & high resistivity linked to C incorporation in GaN films^{1,2}

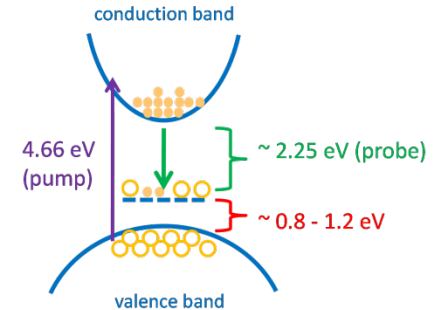
¹ Wickenden, A.E., et al. *J. Crys. Growth* 2003, 54

² Koleske, D.D., et al. *J. Crys. Growth* 2002, 55

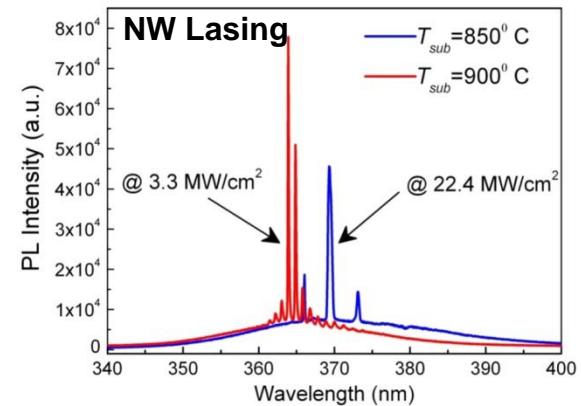
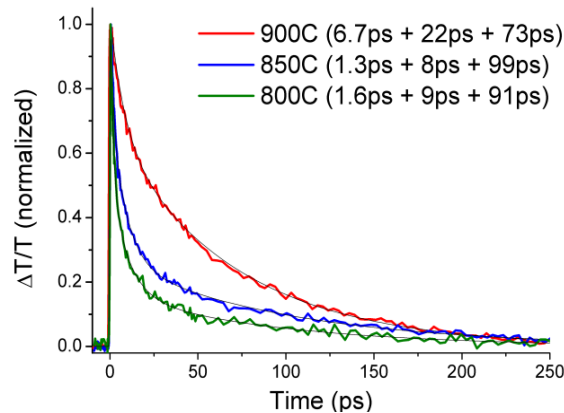
Non-equilibrium carrier dynamics in GaN nanowires



Measures transmission of ultrashort optical pulse (probe) after above-band gap excitation (pump) on a fs timescale



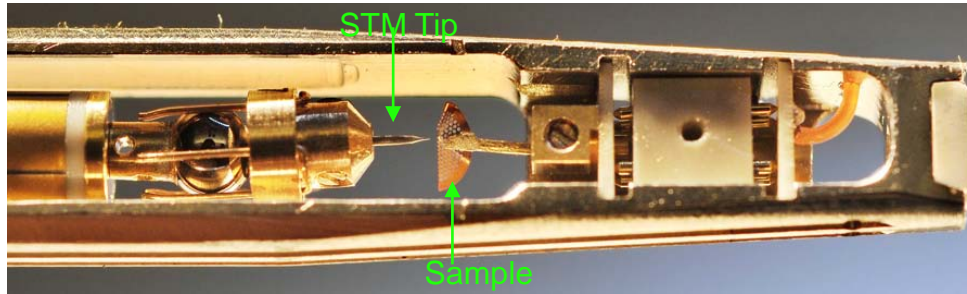
Here, we examine **carrier relaxation** through YL defect states after above-band gap excitation in GaN NWs



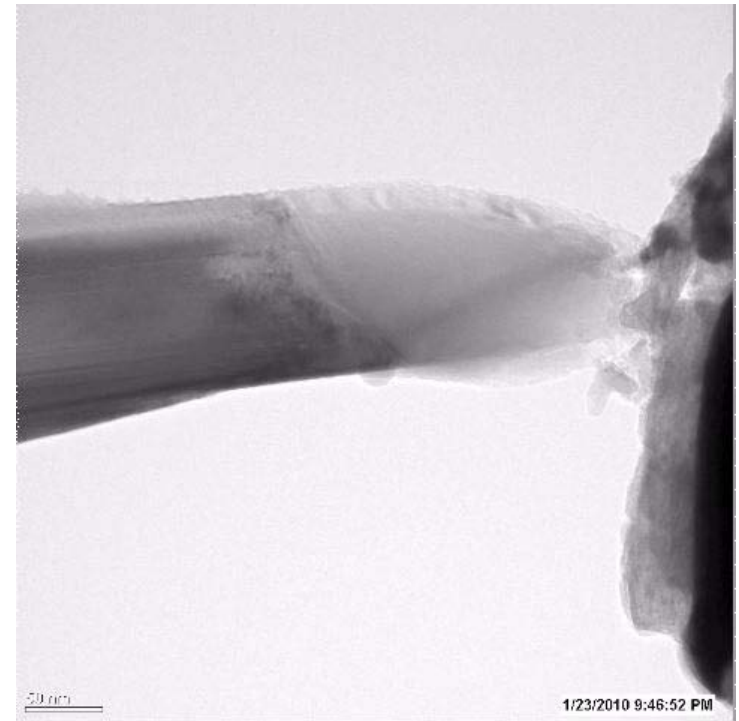
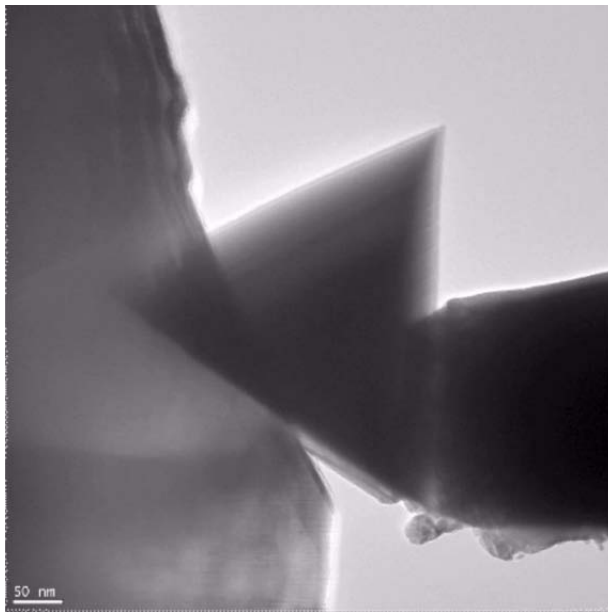
- carrier relaxation rates through YL states increase with decreasing growth temperature due to additional impurity sites that are present at lower growth temperatures.
- defect states also influence the lasing threshold in GaN NWs
- control of the growth temperature can be used to optimize GaN NW-based devices.



In-situ TEM studies – nanowire electrical breakdown



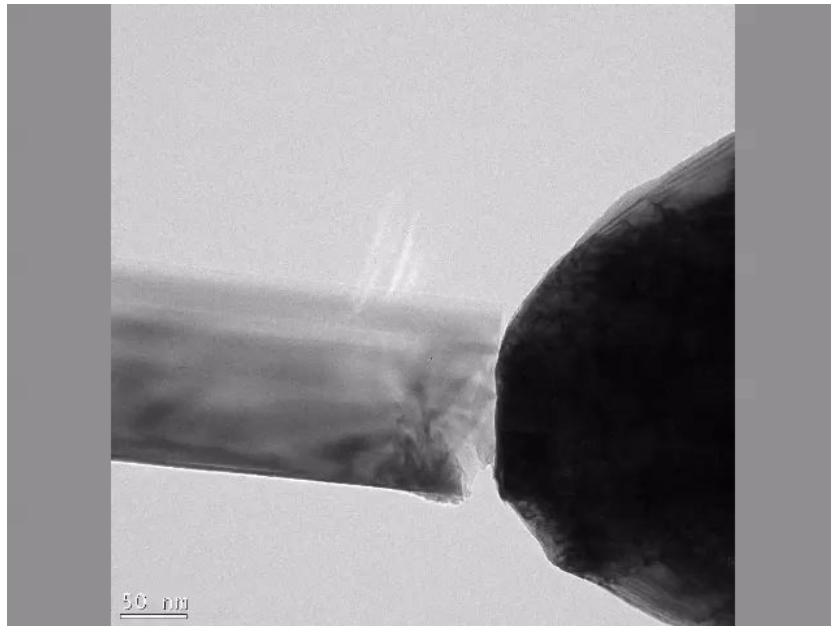
NW decomposition via Joule heating
(relevant for NW devices)





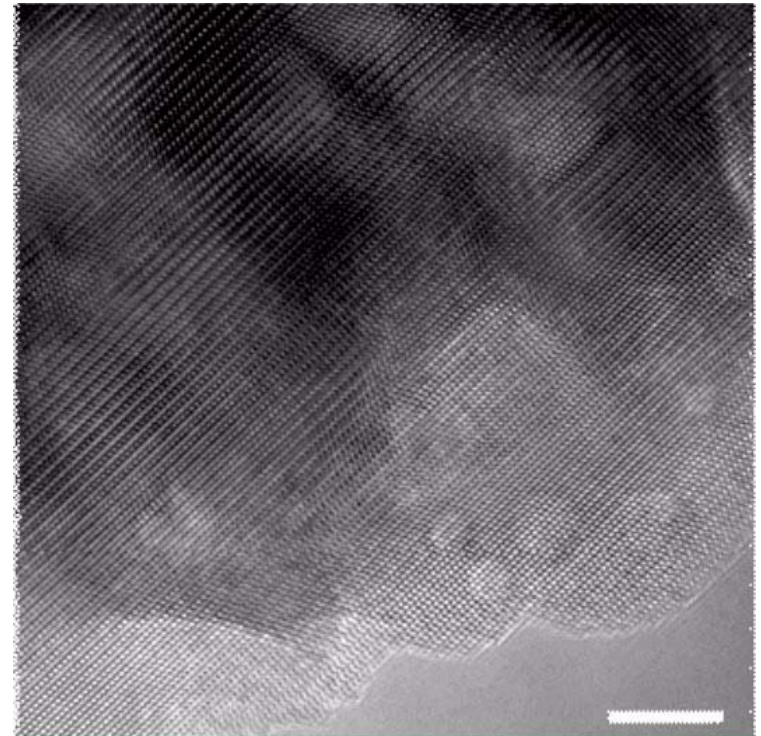
In-situ TEM studies

In-situ deformation



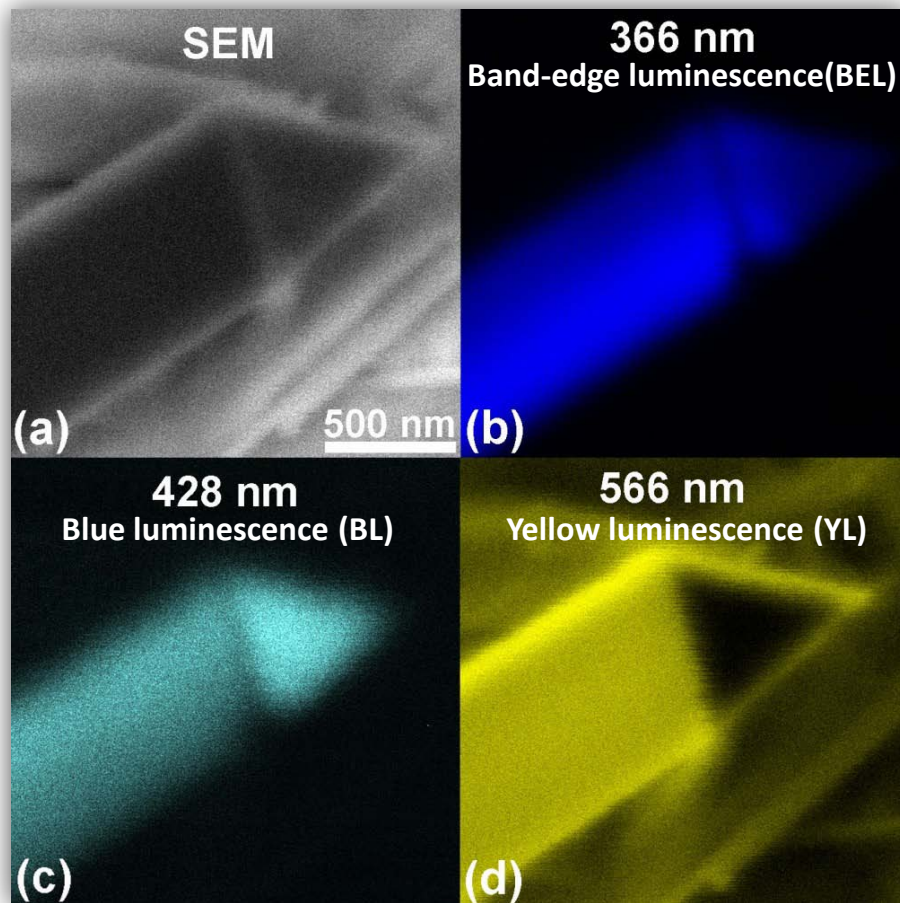
- Dislocation-free NW undergoes non-recoverable plastic deformation
- Mediated by dislocation formation, grain boundary sliding

Void/bubble migration



- “Bubbles” migrate under beam irradiation
- Origin unknown – possible N_2 / H_2 gas?

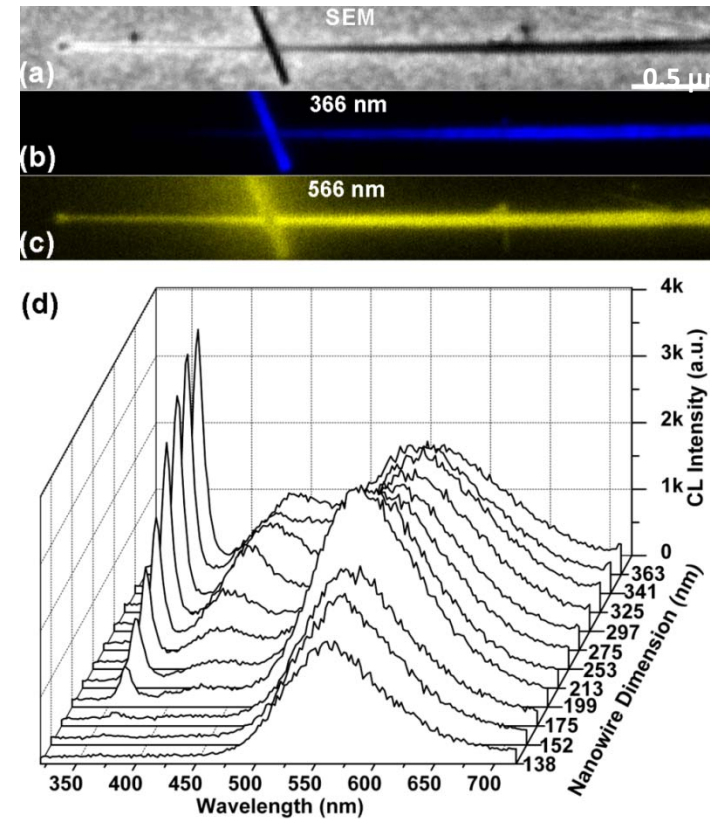
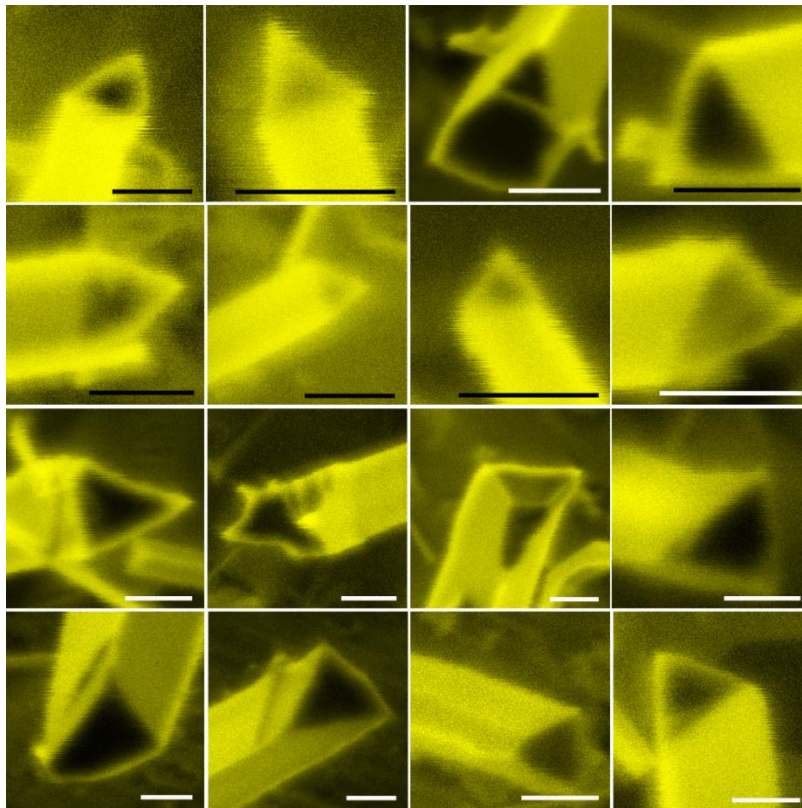
Spatially-resolved CL study of GaN NWs



Nanoscale CL imaging: Cross-section GaN NW

- Band-edge luminescence (BEL) at ~ 366 nm and defect-related blue luminescence (BL) at ~ 428 nm observed in NW core/bulk
- Defect-related yellow luminescence (YL) exhibits strong surface component -- associated with surface states or concentrated near surface region
- Well-known YL in GaN attributed to many possible sources (C, O impurities, Ga vacancies, etc.)
- Isolated Ga vacancies have low diffusion barrier (~ 1.5 eV) & may migrate toward surface during growth
- BL linked to $V_{\text{Ga}}\text{-O}_\text{N}$ ($D \sim 2.2$ eV), less mobile

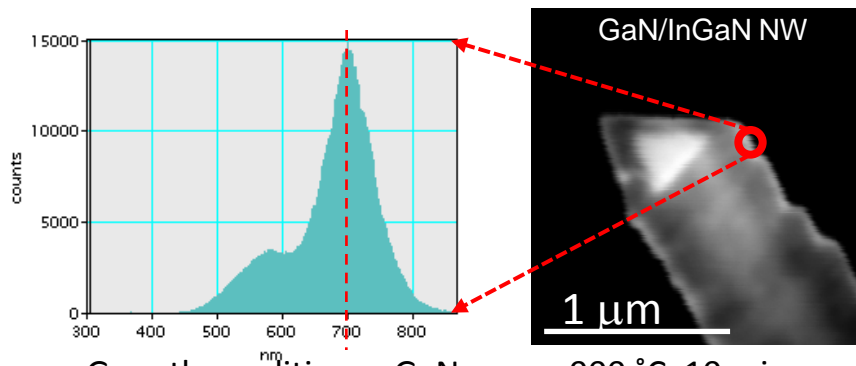
YL surface layer causes “pinch-off” of BEL



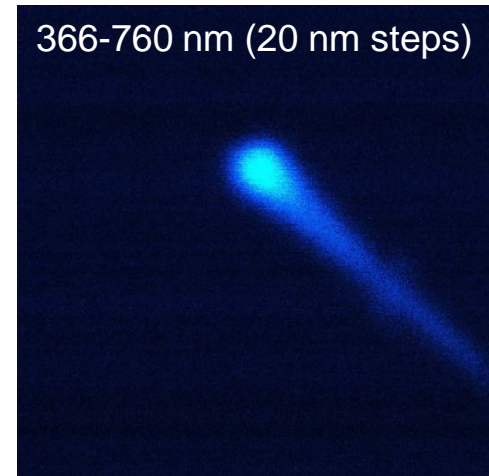
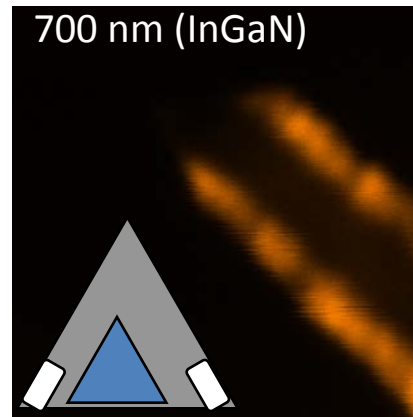
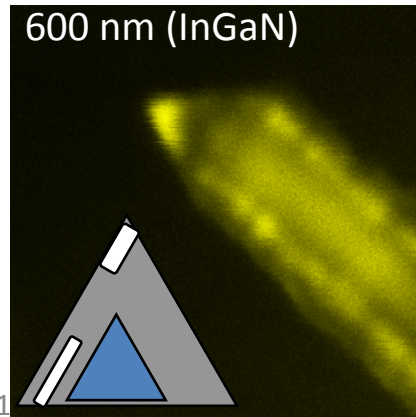
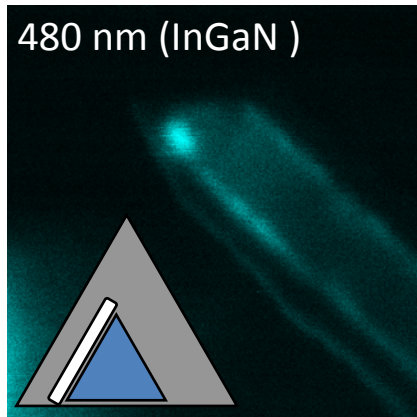
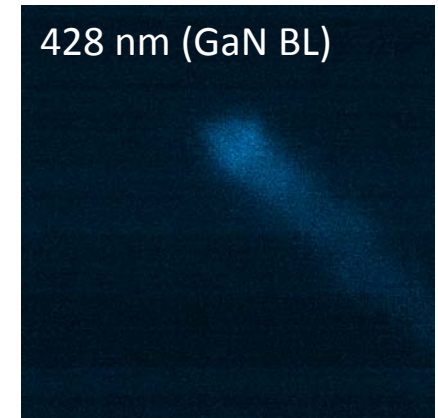
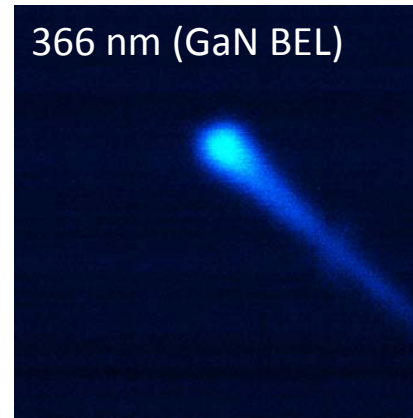
- Tapered nanowire shows “pinch-off” effect
- Spectra taken along tapered NW length, shows “critical diameter” of ~ 160 nm

High Indium Incorporation in GaN/InGaN core-shell NWs

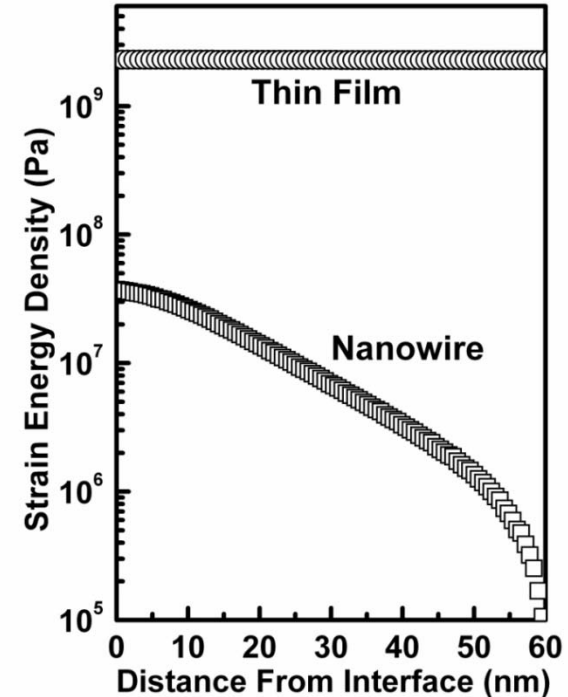
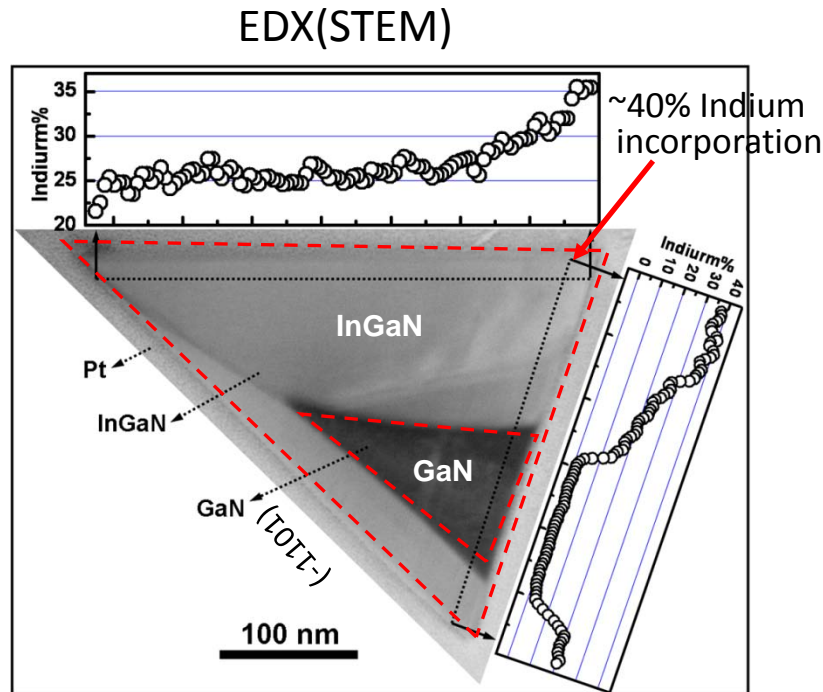
- InGaN: visible wavelengths for solid-state lighting, PV, etc.
- Strain limits practical In incorporation in InGaN thin films (e.g., green-yellow-red gap)



Growth conditions: GaN core – 900 °C, 10 min.
InGaN shell – 760 °C, 60 min.

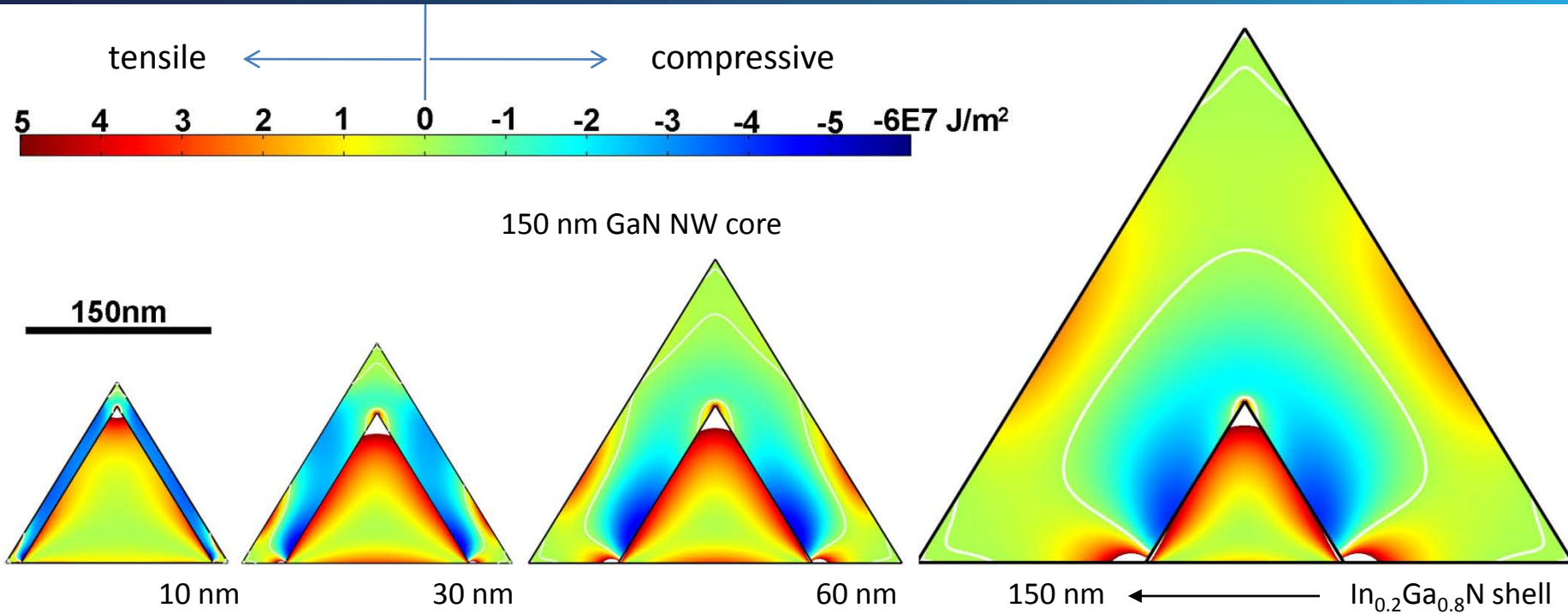


In incorporation in GaN/InGaN core-shell NWs



- InGaN shell growth highly facet-dependent -- no growth on (000-1) c-plane facet
- In concentration increases away from GaN/InGaN interface, highest at corners
- No dislocations observed despite very high In concentration
- Strain in InGaN NW shell much lower than for InGaN thin film

Strain-dependent In incorporation in GaN/InGaN core-shell NWs

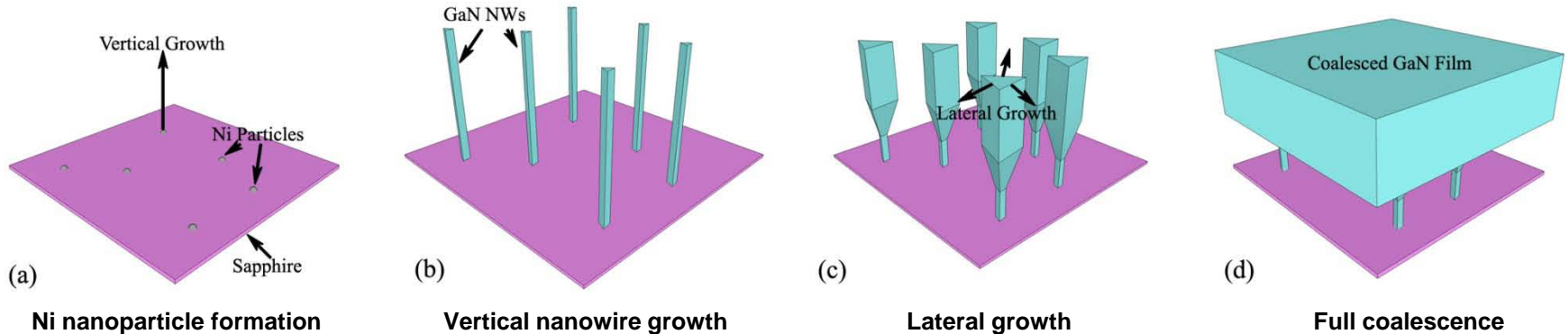


- Finite element models show compressive/tensile strain in GaN core and InGaN shell
- Compressive strain dominates in thinner shells, decreases away from interface and becoming tensile for thicker shells
- Higher In incorporation correlated with lower (compressive) strain regions



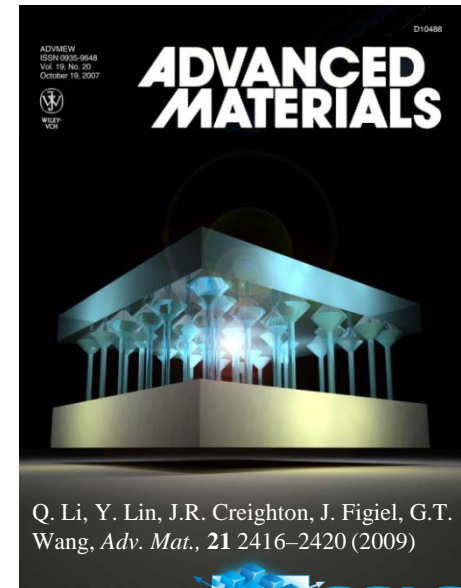
Nanowire-templated lateral epitaxial growth (NTLEG) of high quality GaN

Inexpensive method to reduce dislocation density in GaN films growth on lattice mismatched substrates

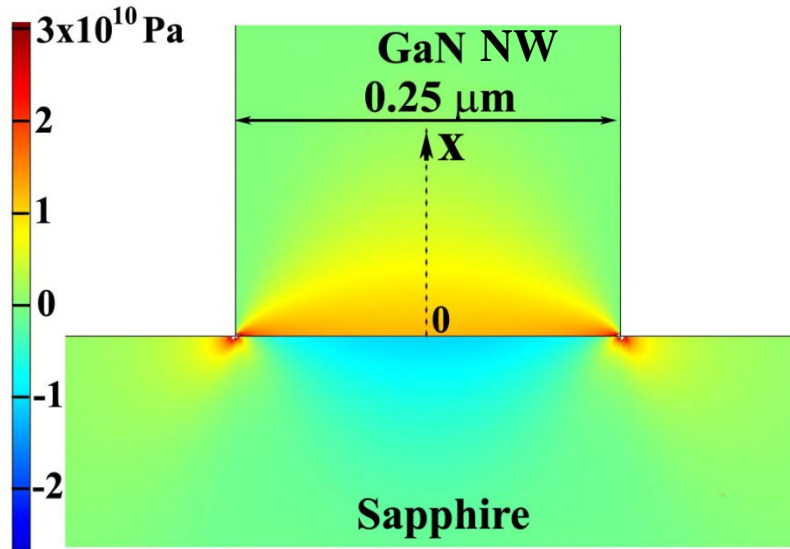


Advantages of NTLEG approach vs. epitaxial lateral overgrowth

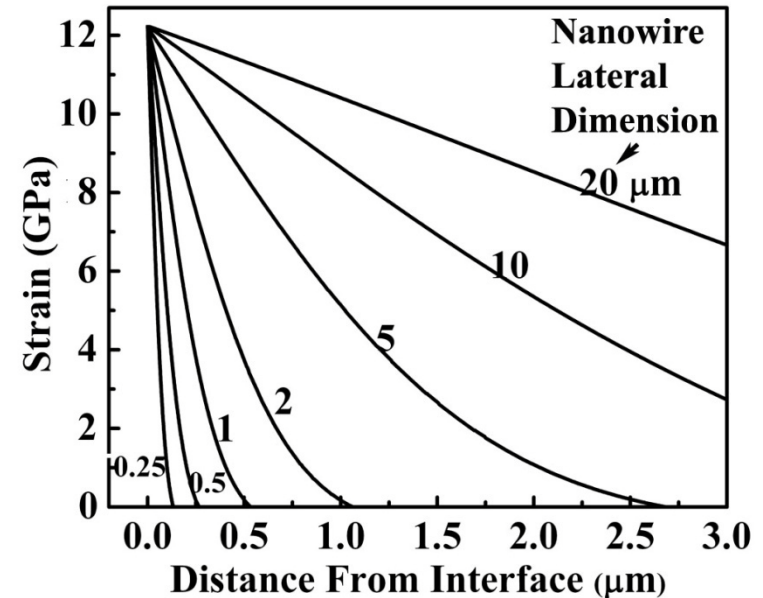
- High quality dislocation-free nanowires as growth template
- *NWs as 3D-compliant nanoscale bridges connecting film & substrate, relieving strain in the film & reducing defects (nanoheteroepitaxy)¹*
- No high defect density “window/stripe” areas
- Low cost (comparable to standard GaN growth on sapphire)
 - Sapphire can be used (potentially even Si)
 - No patterning
 - Single growth step



NTLEG – Nanowire-substrate strain modeling



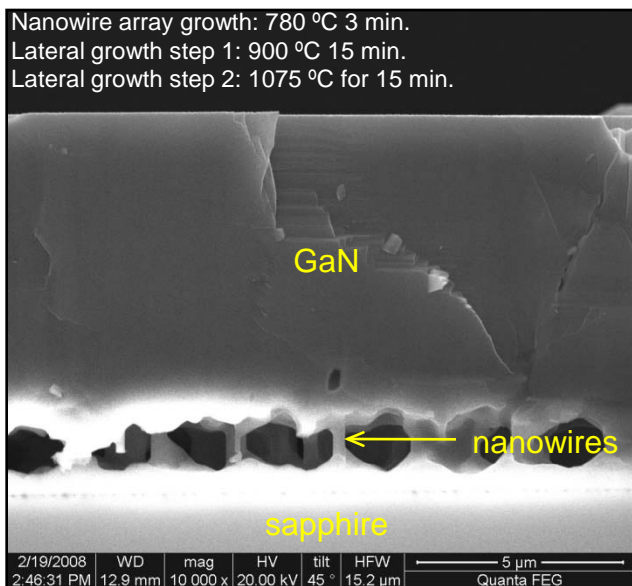
Strain distribution in 250 nm wide GaN NW on sapphire
(15% lattice mismatch between a-plane GaN & r-plane sapphire)



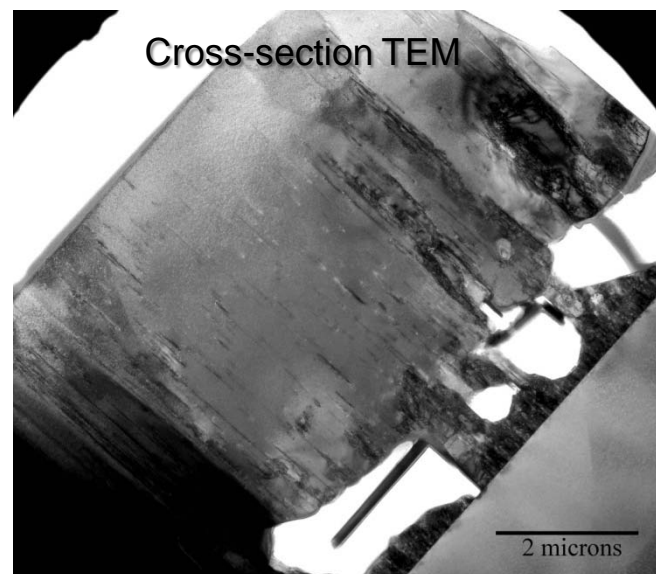
Line plots of the strain decay along the NW center line

- Finite element analysis shows *strain rapidly decays away from nanowire/sapphire interface*.
- The strain decay length (length where strain ~ 0) is ~one-half of the lateral NW dimension
- Shows theoretical basis for strain relief in the NTLEG film, which is distant from strain field caused by lattice/thermal mismatches

NTLEG – Growth & Characterization a-GaN film



Cross-section SEM



Selected previous planar a-plane GaN on r-plane sapphire work:

Method on <i>r</i> -sapp	TDD (cm ⁻²)	SFD (cm ⁻¹)	XRD FWHM (11-20) ¹	Source
NTLEG (This work)	~1x10 ⁹	1.5x10 ⁵	540	This work (Q. Li et al. Adv. Mat., 21, 2416–2420 (2009))
LT nucl. Layer	~3x10 ¹⁰	4x10 ⁵	1040	M. D. Craven et al., Appl. Phys. Lett., 81, 469.(2002)
” “	~7x10 ¹⁰	7x10 ⁵	1290	A. Chakraborty et al. Appl. Phys. Lett., 89, 041903 (2006)
SiNx Nanomask	9x10 ⁹	3x10 ⁵	1040	A. Chakraborty et al. Appl. Phys. Lett., 89, 041903 (2006)
Single-step LEO	10 ⁷ -10 ⁸ (wings)	10 ⁴ -10 ⁵	610	Imer et al. (2007), JCG 306, 330 (2007)
Sidewall LEO	10 ⁶ -10 ⁷	10 ³ -10 ⁴	295	Imer et al. (2007), JCG 306, 330 (2007)



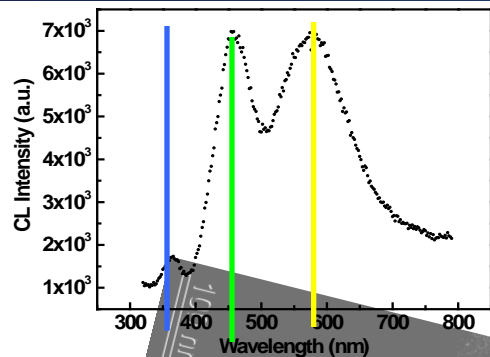
Conclusions

- Electrical & optical studies reveal impact of nanowire growth conditions on properties
- Spatially resolved CL reveals a yellow luminescence surface layer in GaN NWs. YL-related defects may be mobile & migrate to the surface region during growth
- GaN NWs good platform for InGaN growth -- up to 40% In incorporation is observed with no observed dislocations, due to reduced compressive strain
- Aligned growth and NW strain-relaxation leveraged to grow planar GaN films (NTLEG)

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Further questions? gtwang@sandia.gov

Multiquantum well InGaN/GaN nanowires



- CL shows two main InGaN peaks around 460 nm & 580 nm

